Equipment	**Scanning electron microscope Zeiss EVO 50 XVP**
Photo:	
Technical details:	Resolution of 3 nm at 30 kV Beam current in range from 0.5 pA to 5 μA, Image modes: secondary electron image (SE), backscattered electron image (BSE), topography (TOPO), composition (COMPO), shadowed. Additional detectors: infrared camera, probe current EDX Oxford instruments INCA 350 Si detector 10mm2 area, resolution at Mn 133eV.
Applications:	Applied physics, material science
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